



11/B

Box AF 1/22/03
Expedited Procedure Muller
Examining Group 2813
Docket No. 740819-634

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:)
Koji ARITA et al.) Group Art Unit: 2813
Application No.: 09/938,528) Examiner: David S. BLUM
Filed: 08/27/2001)
For: METHOD FOR MANUFACTURING A)
SEMICONDUCTOR DEVICE)

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AMENDMENT

Commissioner for Patents
Washington, D.C. 20231
ATTN: **BOX AF**

Sir:

In response to the Office Action mailed September 11, 2002, the due date for which having been extended one (1) month to January 11, 2003, please amend the above identified application as follows.

IN THE CLAIMS:

Please amend claim 1 as follows:

- SUB C1 7**
1. (Twice Amended) A method for manufacturing a semiconductor device, comprising the steps of:
- forming, in a semiconductor layer formed on a first insulating film, an element isolation groove extending to the first insulating film;
 - depositing a second insulating film so as to partially fill the element isolation groove by using a vapor deposition method;
 - forming an embedded layer on the second insulating film so as to completely fill the element isolation groove; and
 - forming a third insulating film on the embedded layer,
- B1**